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SEP 27 2004

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Hyun-Jae Kim, et al.)
Serial No.: 10/663,081) Group Art Unit:
Filed: September 16, 2003) 2812
For: MASK FOR POLYCRYSTALLIZATION AND)
METHOD OF MANUFACTURING THIN FILM)
TRANSISTOR USING)
POLYCRYSTALLIZATION MASK)

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the restriction requirement mailed on August 27, 2004, and in accordance with the provisions under 37 CFR § 1.115 and 1.143, the Applicants submit the following election for further prosecution on the merits:

Election:

The Applicants hereby provisionally elect Group I, claims 1-13, drawn to a product, classified in class 430, subclass 5+.